



App. No. 09/360,292

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.09/360,292
Filing Date July 22, 1999
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1765
Examiner Ahmed, Shamim
Attorney's Docket No.MI22-1106
Title: Plasma Etching Process

RESPONSE TO APRIL 27, 2005 FINAL OFFICE ACTION
TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

AMENDMENTS

Introductory Comments

In response to the Final Office Action dated April 27, 2005, applicant amends and remarks as follows.